U.S. Department of Commerce, Patent and Trademark Office					Atty Docket No.		Serial No.		
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT					Applicant(s)				
(Use several sheets if necessary)					Robert J. Rafac				
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U.S. Patent Documents									
*Examiner		Document			Filing Date				
Initial		Number	Date_	Name	Class	Subclass	If App	ropriate	
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Foreign Patent Documents									
							Translation		
	'	Document	Date	Country	Class	Subclass	Yes	. No	
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)									
-	A	"Contribution	of polychromatic illumination to optical proximity effects in the context of						
SAT		Deep-UV lithography', A. Kroyan, I. Lalovic, N. R. Farrar, Proc. 21st Annual BACUS Symposium on Photomask Technology and Management, G. T. Dao and B. J. Grenon (Eds),							
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Examiner /	Samuel	A. Turner/	Date Considered	12/13/2006	•				
*EXAMINER:	*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not								
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